

Notice of References Cited	Application/Control No. 09/682,329	Applicant(s)/Patent Under Reexamination OLSCHEWSKI, FRANK	
	Examiner ANH H DO	Art Unit 2624	Page 1 of 1



U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-4,672,559	06-1987	Jansson et al.	382/128
	B	US-4,803,358	02-1989	Kato et al.	250/310
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Li et al., "Three-Dimensional Reconstruction of Microscope images", IEEE Canadian Conference on Electrical and Computer Engineering, 9-1993, Vol. 2, pps. 1013-1016
	V	Hagedorn et al., "A System for Measuring Surface Facet Orientation from Atomic Force Microscope Data", IEEE Proceedings 10-1996, pps. 397-400, 508
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.